

# Plasma Source Manufacturing Agreement

Seldon Custom Plasmas agrees to manufacture multipole plasma sources for Chung Song Systems, Ltd. under the following conditions:

Seldon recognizes that Chung Song Systems, Ltd. is interested in the effectiveness of the multipole plasma source in providing the desired process results on the wafer. However, Seldon is not in a position to guarantee such process results, since a number of factors other than the effectiveness of the source contribute to these process results.

Seldon is confident that the characteristics of the multipole source make excellent process results possible, especially in the 1 to 10 millitorr pressure range, and Seldon is prepared to exert every effort to assist Chung Song Systems, Ltd. in achieving these results.

The initial decision regarding the suitability of the multipole source for use with a Chung Song Systems, Ltd. chamber must be based on experience using a multipole source on that chamber. Accordingly, Seldon is prepared to provide a prototype multipole source designed to match a Chung Song Systems, Ltd. chamber so that the desired suitability can be confirmed.

After Chung Song Systems, Ltd. is convinced through prototype source test results that they wish to use the Seldon multipole source design, then mechanical, electrical, and plasma generation specifications can be established, and purchase contracts can be written.

The cost of the first multipole sources will be \$40,000 each for chamber interior diameters up to 40 cm and \$60,000 each for chamber interior diameters greater than 40 cm. The license fee will be in addition to the purchase price.

At the option of Chung Song Systems, Ltd., multipole sources using principles described in U.S. patent # 5,435,881 can be manufactured by either Chung Song Systems, Ltd., or by a separate organization authorized by Chung Song Systems, Ltd., provided that Chung Song Systems, Ltd. is responsible for assuring that every unit manufactured has a license label authorized by Seldon permanently attached. Failure to conform to this requirement will result in termination of the license agreement between Seldon Custom Plasmas and Chung Song Systems, Ltd.

If Chung Song Systems, Ltd. decides to manufacture or to have manufactured multipole plasma sources, Seldon will provide proprietary information on sources of materials and on manufacturing and source design techniques on the condition that Chung Song Systems, Ltd. agrees not to divulge this proprietary information to any third party.

John Seldon Ogle June 3, 1997